

Fazhi Song

List of Publications by Year in descending order

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papers

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| # | ARTICLE | IF | CITATIONS |
|---|--|------|-----------|
| 1 | Iterative Learning Identification and Compensation of Space-Periodic Disturbance in PMLSM Systems With Time Delay. IEEE Transactions on Industrial Electronics, 2018, 65, 7579-7589. | 7.9 | 53 |
| 2 | Data-Driven Feedforward Learning With Force Ripple Compensation for Wafer Stages: A Variable-Gain Robust Approach. IEEE Transactions on Neural Networks and Learning Systems, 2022, 33, 1594-1608. | 11.3 | 34 |
| 3 | Learning Control for Motion Coordination in Wafer Scanners: Toward Gain Adaptation. IEEE Transactions on Industrial Electronics, 2022, 69, 13428-13438. | 7.9 | 33 |
| 4 | Data-Driven Iterative Feedforward Tuning for a Wafer Stage: A High-Order Approach Based on Instrumental Variables. IEEE Transactions on Industrial Electronics, 2019, 66, 3106-3116. | 7.9 | 27 |
| 5 | An Internal Model Based Iterative Learning Control for Wafer Scanner Systems. IEEE/ASME Transactions on Mechatronics, 2019, 24, 2073-2084. | 5.8 | 19 |
| 6 | Intelligent measurement and compensation of linear motor force ripple: a projection-based learning approach in the presence of noise. Measurement Science and Technology, 2018, 29, 064004. | 2.6 | 5 |
| 7 | Model-Based ILC with a Modified Q -Filter for Complex Motion Systems: Practical Considerations and Experimental Verification on a Wafer Stage. Complexity, 2018, 2018, 1-11. | 1.6 | 1 |
| 8 | Enhancing Accuracy and Numerical Stability for Repetitive Time-Varying System Identification: An Iterative Learning Approach. IEEE Access, 2020, 8, 25679-25690. | 4.2 | 1 |
| 9 | Modeling and sliding-mode control of wafer stage in lithography machines. , 2016, , . | | 0 |